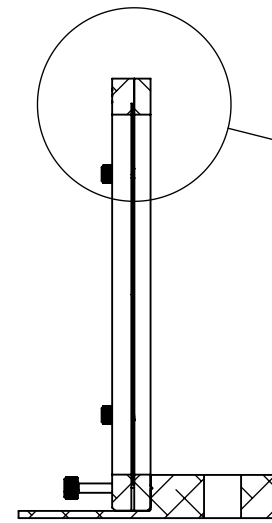
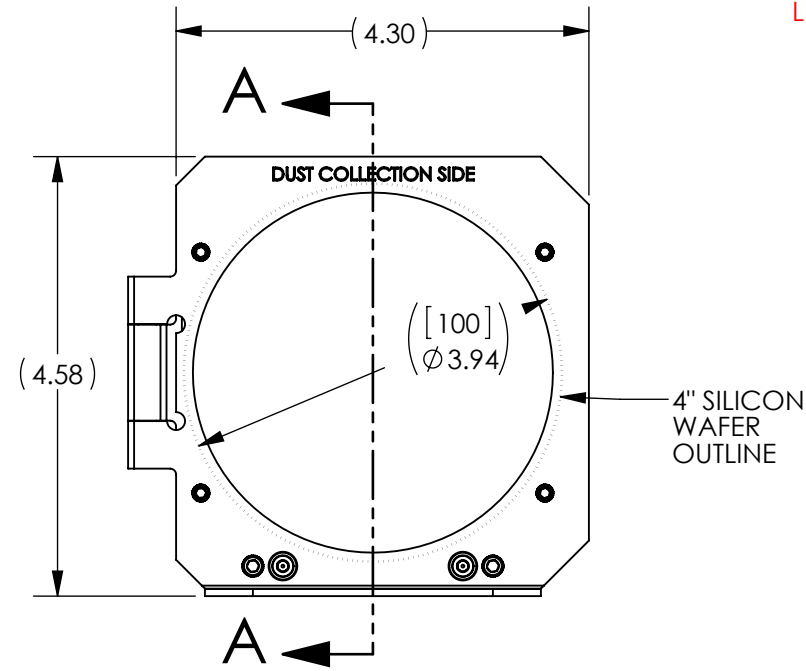


8 7 6 5 4 3 2 1

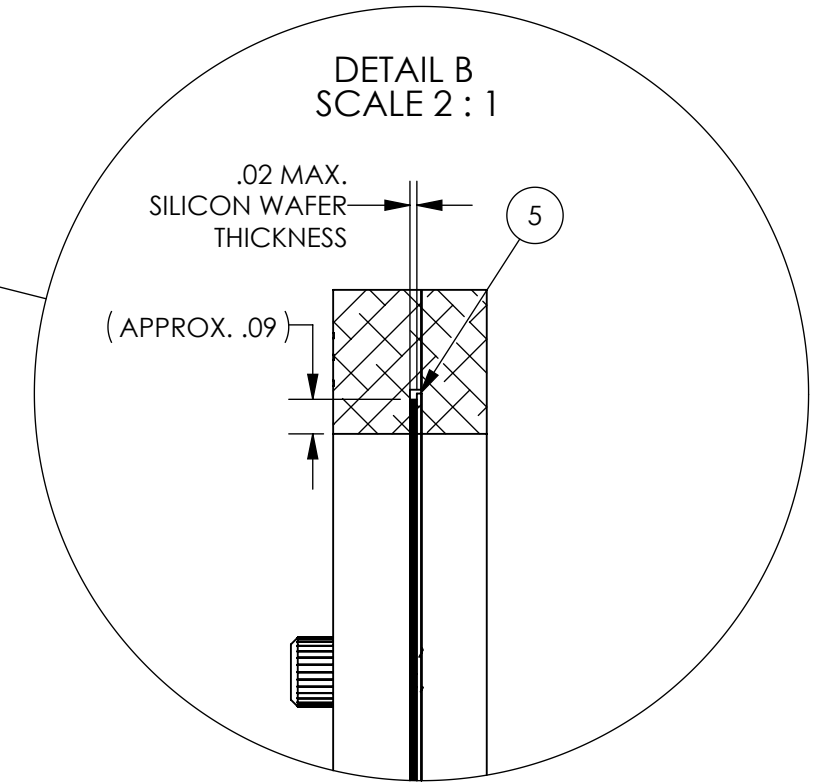
SEE LIGO T1300014 FOR VERTICAL WAFER HOLDER LOCATIONS.

NOTE: WAFER STAND CAN ALSO BE USED HORIZONTALLY BY SIMPLY REMOVING THE BASE + 6-32 CAPTURED SCREWS. REFER TO LIGO T1300014: ALIGO, BSC FLOORING + HAM ISI, WITNESS SAMPLE PLACEMENT GUIDELINES

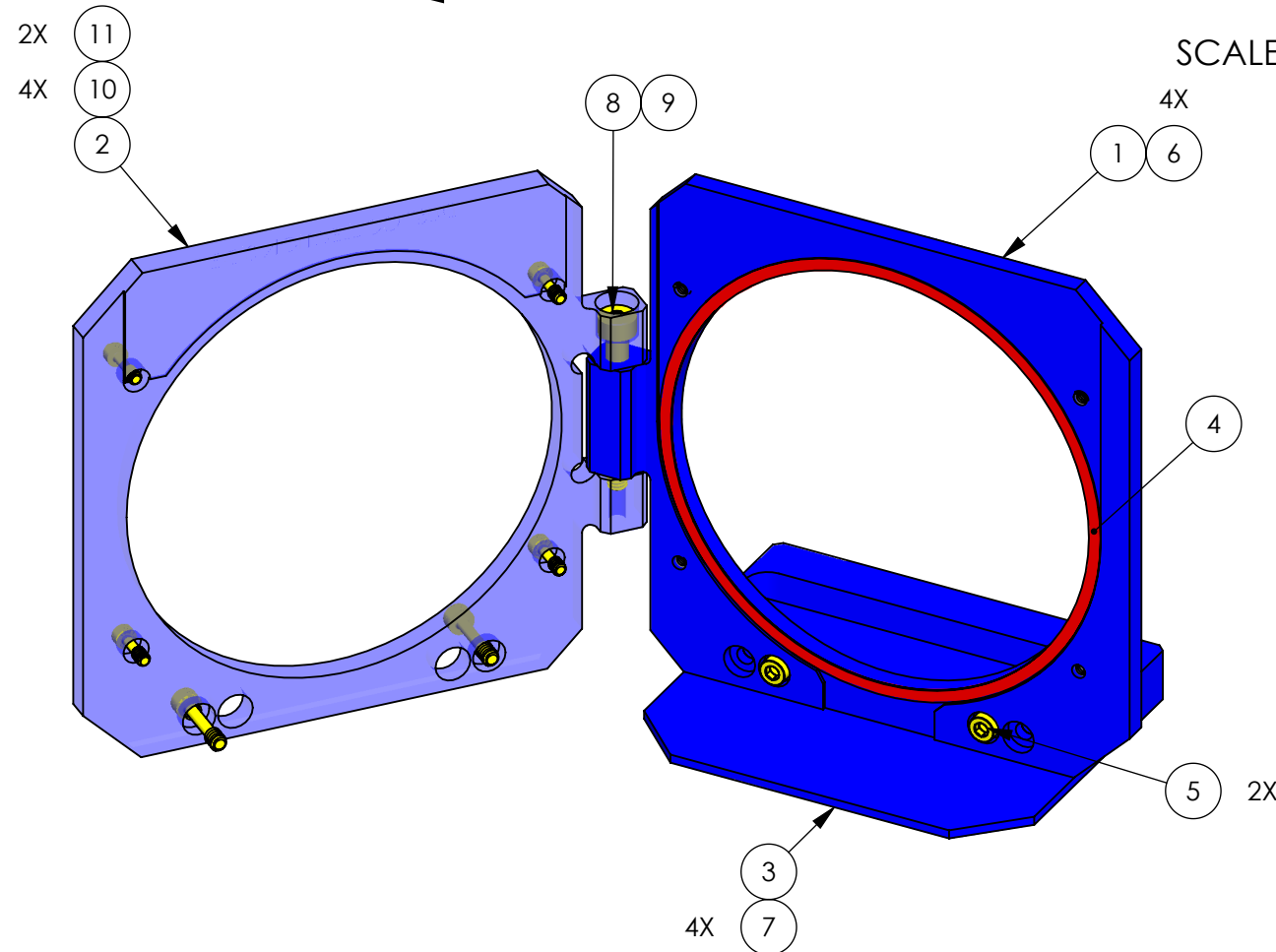
REV.	DATE	DCN #	DRAWING TREE #
v1	20 MAR 2013	E1300202-x0	-
v4	07 MAR 2014	E1400134-x0	-
-	-	-	-



SECTION A-A
SCALE 1 : 2



DETAIL B
SCALE 2 : 1



ISO VIEW
(SHOWN OPEN)

ITEM NO.	PART NUMBER	DESCRIPTION	MATERIAL	QTY.
11	95966A231 McMaster-Carr OR EQ.	SCREW, SHC, 6-32 X .63 LG. (CAPTIVE)	18-8 SSSL	2
10	95966A130 McMaster-Carr OR EQ.	SCREW, SHC, 4-40 X .38 LG. (CAPTIVE)	18-8 SSSL	4
9	99842A113 McMaster-Carr OR EQ.	WASHER, WAVE, NO. 10	18-8 SSSL	1
8	94035A209 McMaster-Carr OR EQ.	SCREW, SHC, 8-32 X 1.25 LG. X 3/16 SHANK (SHOULDER)	18-8 SSSL	1
7	1185-06EN207 EMHART OR EQ.	HELICOIL, 6-32 X 1.5 DIA.	NITRONIC 60	4
6	1185-04EN168 EMHART OR EQ.	HELICOIL, 4-40 X .168 LG.	NITRONIC 60	4
5	MS16995-18 OR EQ.	SCREW, SHC, 6-32 X .50 LG.	18-8 SSSL	2
4	D1300521	SHIM, 4 IN WAFER	304 SSSL	1
3	D1300274	aLIGO, 4 in. SILICON WAFER STAND, BASE	6061-T6 Al	1
2	D1300273-102	aLIGO, 4 in. SILICON WAFER STAND, HOUSING (FRONT)	6061-T6 Al	1
1	D1300273-101	aLIGO, 4 in. SILICON WAFER STAND, HOUSING (BACK)	6061-T6 Al	1

PARTS LIST

NOTES AND TOLERANCES: (UNLESS OTHERWISE SPECIFIED)

MATERIAL N/A FINISH N/A μinch

CALIFORNIA INSTITUTE OF TECHNOLOGY MASSACHUSETTS INSTITUTE OF TECHNOLOGY
PART NAME aLIGO, 4 in. SILICON WAFER STAND ASSEMBLY
SYSTEM ADVANCED LIGO **SUB-SYSTEM** SYS
DESIGNER E.SANCHEZ **MAR 19 2013** **SIZE** DWG. NO. **D1300275** **REV.** v4
DRAFTER E.SANCHEZ **MAR 20 2013**
CHECKER SEE DCC **APPROVAL** SEE DCC
SCALE: 1:2 **PROJECTION:** **SHEET 1 OF 1**

8 7 6 5 4 3 2 1

D1300275_Aligo, 4 in. Silicon Wafer Stand Assembly, PART PDM REV: X-011, DRAWING PDM REV: X-011